



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

RECEIVED AF  
JAN 26 2004  
TC 1700

re the Application of: HATTORI, Kazuhiro

Serial No.: 09/816,784

Group Art Unit: 1765

Examiner: Lan Vinh

Filed: March 26, 2001

P.T.O. Confirmation No.: 5542

OK to enter  
LV  
2/5/2004

For: DRY ETCHING METHOD, MICROFABRICATION PROCESS AND DRY ETCHING MASK

RESPONSE UNDER 37 CFR §1.116

- EXPEDITED RESPONSE -  
GROUP ART UNIT 1765

MAILSTOP AF

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

January 22, 2004

Sir:

In response to the Office Action dated **October 22, 2003**, please amend the above-identified application as follows: